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PATENT NUMBER and ISSUE DATE

U.S. **UTILITY** Patent Application

	APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	_	EXAMINER				
	10088306	03/18/2002	034	259	3749	ON	ralley, tathing	4			
	**APPLICANT Koutarou;	S: Ohno H	iromoto; (Ohi Toshio; Yo	shida S		hhira Manabu; Tanaka				
AVAILABLE COPY	**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP01/06164 07/17/2001 WHICH CLAIMS BENEFIT OF 60/230,811 09/07/2000 * AND CLAIMS BENEFIT CF 60/261,265 01/16/2001 * (*)Data provided by applicant is not consistent with PTO records.										
וסבט	** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-217610 07/18/2000 JAPAN 2000-397269 12/27/2000 JAPAN 2001-189388 06/22/2001										
16	PG-PUB DO N			RESCIN	_□ □						
	oreign priority claimed		□ no			ATTORNEY DOCKET NO Q60716					
	TITLE: Cleaning gas for semiconductor production equipment U.S.DEPT. OF COMMUPAT 2-TM-PTO-4361/Rev 12-941										
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NOTICE OF ALL	OWANCE MAILED		CLAIMS ALLOWED						
		Assistant Examiner	Total Claims		Print Claim for O.G				
ISS	UE FEE	• •	DRAWING						
Amount Due	Date Paid	·	Sheets Drwg.	Figs.Drwg.	Print Fig.				
		Primary Examinor	ļ	L	<u></u>				
TEF	RMINAL	PREPARED FOR ISSUE	Application Examiner						
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